

# Experimental Report

25/11/2014

<b>Proposal:</b>	<b>DIR-130</b>	<b>Council:</b>	4/2014	
<b>Title:</b>	Characterisation of Interfaces with delamination problems within the framework of the IRT nanoelectronics			
<b>This proposal is a new proposal</b>				
<b>Research Area:</b>				
<b>Main proposer:</b> IMBERT GREGORY				
<b>Experimental Team:</b> IMBERT GREGORY SEGURA RUIZ Jaime Alberto PONARD Anne				
<b>Local Contact:</b> GUTFREUND Philipp CUBITT Robert				
<b>Samples:</b> Si SiOCH SiN				
<b>Instrument</b>	<b>Req. Days</b>	<b>All. Days</b>	<b>From</b>	<b>To</b>
D17	1	1	16/11/2014	17/11/2014
<b>Abstract:</b>				

## **Report on the Director's Discretion Time experiment DIR-130**

**Title:** Characterisation of interfaces with delamination problems within the framework of the irt nanoelectronics

**Context:** IRT NanoElec feasibility tests

**Main proposer:** Gregory IMBERT – ST Microelectronics

**Date:** 16 November, 2014

In the framework of the IRT NanoElec and after the success of previous experiments on the study of delamination at the a-C/SiO<sub>2</sub> interface performed in collaboration with STM, this study has been extended to other type of interfaces which are very relevant in the ICs manufacturing and that suffer also from delamination problems. The main objective of the experiment DIR-130 was to start the feasibility study with the interfaces between SiC, SiN, and SiCN, with low-k and ULK materials (porous or not). Determining the profile of hydrogen concentration in these interfaces and the layers involved, and its correlation with the parameters used for their deposition is expected to help in the improvement of the adhesion characteristics of this type of structures.

Eight samples with interfaces between SiC<sub>x</sub>N<sub>1-x</sub> and different low-k and ULK materials were scheduled for measurements:

Slot 1: SiC (800A) / ULK1 (2100A)

Slot 2: SiC (800A) / ULK1 (2100A)

Slot 3 : SiCN (350A)/ ULK 1 (2300A)

Slot 6: SiCN (350A)/ ULK 2 (2000A)

Slot 8 : SiCN (350A)/ ULK 3 (2000A)

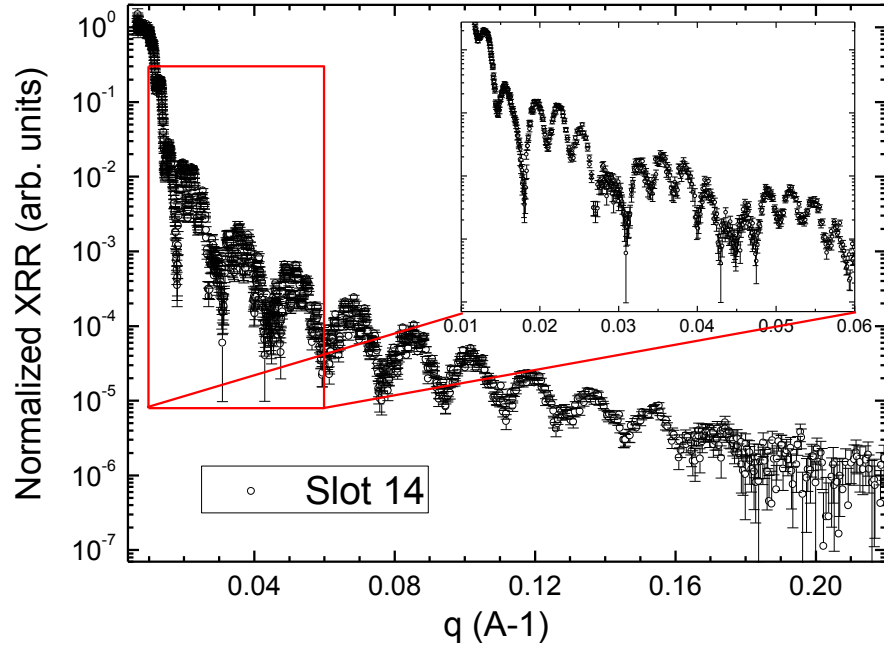
Slot 10: SiCN (350A)/ ULK 4 (2000A)

Slot 12: SiN (400A)/ ULK 1 (2300A)

Slot 14: SiCN (350A)/ low k 1 (1800A)

Due to the high resolution needed for some samples, only three samples (underlined) were measured during the experiment DIR-130. Therefore, five more samples are missing and one more day will be needed to finish the measurements on the full set of samples.

Figure 1 shows a representative experimental neutron reflectivity curve measured from the sample Slot 14, having a Si substrate 300 mm-thick, on top of which a SiCN layer, 350A-thick and subsequently a low-k SiCOH layer, 1800A-thick have been deposited. The inset shows a detail of the oscillations in the q-range 0.01-0.06 Å<sup>-1</sup>.



**Figure 1 :** Experimental neutron reflectivity from sample Slot 14, corresponding to an interface SiCN ( $\sim 350\text{\AA}$ )/ low-k 1  $\sim 1800\text{\AA}$ . The inset shows a detail of the oscillations in the  $q$ -range  $0.01$ - $0.06\text{ \AA}^{-1}$ .

Preliminary fitting of the experimental data suggests there is hydrogen inside the underneath SiCN layer, and that there is an intermediate layer with a very high H-concentration in between the SiCN and the low-k layer. However, in order to have define a clear model that allows a better fitting of the entire set of samples, the remaining samples should be measured and included in the study. Furthermore, complementary X-ray reflectivity measurements should be performed in the full set of samples in order to corroborate the presence of H, and to determine its concentration.